

10. (New) The MEMS device of claim 2, wherein the movable element moves
in a direction parallel to the plane of the substrate.

Control

11. (New) The MEMS device of claim 3, wherein the movable element moves
in a direction parallel to the plane of the substrate.

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12. (New) The MEMS device of claim 4, wherein the movable element moves
in a direction parallel to the plane of the substrate.
